

Substitute Form PTO-1449 (Modified)	U.S. Department of Commerce Patent and Trademark Office	Attorney's Docket No. 10559-928001	Application No. 10/813,453
Information Disclosure Statement by Applicant (Use several sheets if necessary) (37 CFR §1.98(b))		Applicant Richard Schenker et al.	
		Filing Date March 29, 2004	Group Art Unit 2852

U.S. Patent Documents

Examiner Initial	Desig. ID	Document Number	Publication Date	Patentee	Class	Subclass	Filing Date If Appropriate
	AA						
	AB						
	AC						
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	AG						
	AH						

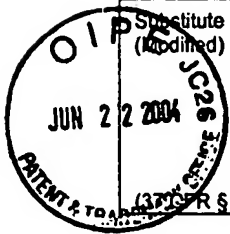
Foreign Patent Documents or Published Foreign Patent Applications

Examiner Initial	Desig. ID	Document Number	Publication Date	Country or Patent Office	Class	Subclass	Translation	
							Yes	No
	AI							
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	AK							
	AL							
	AM							

Other Documents (include Author, Title, Date, and Place of Publication)

Examiner Initial	Desig. ID	Document
RS	AN	Richard Schenker et al., "Material Limitations to 193-nm Lithographic System Lifetimes", SPIE Vol. 2726, pgs. 698-706
RS	AO	Richard E. Schenker et al., "Ultraviolet-induced densification in fused silica", J. Appl. Phys. 82 (3), August 1, 1997, pgs. 1065-1071
RS	AP	G. de Zwart et al., "Performance of a Step and Scan System for DUV Lithography", SPIE Vol. 3051, pgs. 817-830
	AQ	

Examiner Signature <i>RS</i>	Date Considered 11/2/08
EXAMINER: Initials citation considered. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.	



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FL	AQ	Adam et al., "Polarization Effects in Immersion Lithography," Proc. of SPIE, Vol. 5377, pp. 329-342 (2004)
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	AS	
	AT	

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